Facile Integration of Ordered Nanowires in Functional Devices

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ABSTRACT: The integration of one dimensional (1D) nanostructures of non-industry-standard semiconductors in functional devices following bottom-up approaches is still an open challenge that hampers the exploitation of all their potential. Here, we present a simple approach to integrate metal oxide nanowires in electronic devices based on controlled dielectrophoretic positioning together with proof of concept devices that corroborate their functionality. The method is flexible enough to manipulate nanowires of different sizes and compositions exclusively using macroscopic solution-based techniques in conventional electrode designs. Our results show that fully functional devices, which display all the advantages of single-nanowire gas sensors, photodetectors, and even field-effect transistors, are thus obtained right after a direct assembly step without subsequent metallization processing. This paves the way to low cost, high throughput manufacturing of general-purpose electronic devices based on non-conventional and high quality 1D nanostructures driving up many options for high performance and new low energy consumption devices.
1. INTRODUCTION

One dimensional (1D) nanostructures offer a convenient path for the synthesis of high-quality, almost defect free, crystals of non-industry-standard semiconductor materials, such as metal oxides (MOX) [1,2]. However, the integration of these materials in functional devices, with the necessary degree of order and complexity, is an open challenge that still hampers the exploitation of their potential in full [2,3]. Current bottom-up approaches rely on a complex combination of positioning methods (e.g. nanomanipulation, self-assembly, di/electrophoresis, etc.) [3–5], and connecting methods (e.g. UV, Electron/Ion Beam, Soft lithographies) [6–8]. This strategy is however far from reconciling technical requisites with cost requirements of the industry.

A decade of research efforts shows that the most advantageous nanodevice configuration requires either a single (or a few) nanowires running parallel between two electrodes [9] to thus build up a well-defined conduction channel to be easily modulated by external stimuli (e.g. chemical or biological agents [10,11], light or radiation [12], external electric fields [13,14], etc.). This means explicitly avoiding random wire-to-wire conduction paths which inevitably appear in devices based on randomly oriented mats of 1D nanostructures [15].

In the particular case of metal oxide nanowire-devices, this configuration has successfully led to a high number of applications and proof-of-concept prototypes, proving their interest in high temperature and power electronics, in which highly miniaturized field-effect transistors of wide-band gap semiconductor are sought after [16–18].

On the one hand, and regarding gas detection applications, nanowire-based metal oxide sensors [19,20] display important advantages only accessible in ordered configurations [15]. Firstly, the large surface-to-volume ratio of nano-sized materials provides a systematic way to increase the influence of surface phenomena, such as the response to gases [21]. Secondly, nanowires are
typically enclosed by well-terminated surfaces in well-defined crystal orientations, offering a reduced set of interaction sites with gases that render better reaction control, and in general good signal stability [15]. Thirdly, the response dynamics of one or a few nanowires is theoretically faster, if compared to porous layers made of nanoparticles, since all the sensing material is simultaneously exposed to the changes in the gaseous environment [15]. Last but not least, the self-heating effect [22] of nanowire devices can be used to dramatically reduce the power consumption typical of standard MOX sensors (from mW in microdevices to μW in self-heated nanowires[23]) with faster heating/cooling times (in the ranges of ms [24]), in temperature modulated applications.

On the other hand and as far as photodetection applications go, metal oxide nanowires show high intrinsic photoconductive gain values [12,25] mainly linked to the high crystallinity and ultimately caused by the electron-hole separation processes at the surface [26]). Additionally, in contrast with structures based on randomly oriented materials, parallel nanowire arrangements enable uniform light absorption through all the photoconductor material. All in all, MOX nanodevices offer a big potential to build up highly-sensitive photodetectors [27].

Anyhow, all these applications are mostly limited by the lack of simple, cost effective and scalable methods to transfer, precisely position and interconnect nanowires. Among the most promising approaches, macroscopically driven dielectrophoresis [5] seems to address the manipulation concerns in a cost effective manner; but so far, only for selected materials [5,28], and in highly specialized electrode configurations [4,18] and usually followed by a contact fabrication step.

Here, we present a facile and high throughput methodology to build up ordered arrangements of metal oxide nanowires, between a pair of conventional electrodes without the need of any
subsequent micromanipulation, lithography or post processing technique. Our results prove that the method, based on dielectrophoresis, is flexible enough to integrate different types of metal oxide nanowires (such as SnO$_2$, ZnO, TiO$_2$, etc.) and attain the functionalities and the advantages expected from individual nanowires.

2. METHODS

2.1. Materials

To demonstrate the flexibility of our method, three different metal oxide nanowires were used as a proof of concept.

First, crystalline SnO$_2$ nanowires were produced by chemical vapor deposition (CVD) of a molecular precursor [Sn(OtBu)$_4$], catalyzed with Au on top of a Si wafer and following a procedure reported elsewhere [29–31]. The products were longer than 15 µm with typical diameters of 30 ± 10 nm.

Second, ZnO nanowires were obtained by a hydrothermal process reported earlier [32]. In brief, an 80 nm thick seed layer of ZnO was sputtered on indium-doped tin oxide (ITO) glass. The ITO glass was then placed in the growth solution consisting of 0.02 M zincnitrate, 0.015 M hexamethylenetetramine (HMTA), 0.004 M polyethyleneimine (end-capped, molecular weight 800 g/mol) and 0.024 M ammonium hydroxide. The solution was heated to 88°C, and after 3 hours, ZnO nanowires of about 6 µm in length with diameters from 120 to 180 nm were obtained. The resulting ZnO arrays were finally rinsed with Mili-Q water and dried in nitrogen flow.

Third, TiO$_2$ nanowires were obtained by ALD conformal coating of silicon nanowires growth (typical diameter of 100 nm and 5-7 µm in length) by CVD with a conventional method [33].
Tetrakis(dimethylamino)titanium(IV) (TDMAT) was used as a titanium source during the ALD process and water as an oxidizing agent. Growth temperature was fixed at 250°C with a sequence of 5 seconds of TDMAT followed by 5 seconds of water. A total of 2500 cycles were applied to obtain 100 nm of TiO₂, corresponding to a growth rate of 0.4 Å/cycle.

As for the substrates, commercial microhotplates (μHP) with Au Inter Digital Electrodes (IDE) from Cambridge CMOS Sensors (www.ccmoss.com) were used. These devices were originally designed to accommodate a gas sensitive layer across two IDE electrodes. No modification of the general-purpose IDE design was made to facilitate the here-proposed integration method. Gold is inert to oxidation and the rough Au surface provides better attachment to the later deposited nanowire, according to preliminary tests. The IDEs spanned a circular area of 250 μm in diameter and the gap between the IDE fingers was 10 μm. In order to reach the optimum operating temperatures, the devices also integrate a microheating element made of tungsten, and buried under the IDEs within SiO₂ insulation, following an architecture reported elsewhere [34]. Unlike polysilicon heaters, the tungsten heaters offer a much higher stability at high temperatures. The circular SiO₂ insulating membrane obtained by Deep Reactive Ion Etching (DRIE) embedding the IDEs/heater had a diameter of about 640 μm. IDEs, and associated bond pads, were manufactured post CMOS sequence. The maximum temperature the μHP can reach is about 700°C, while the power consumption is only about 55 mW at 450°C. In this work, the heating element was solely used for test and calibration purposes.

2.2. Integration methodology

The as-grown nanowires were first removed from their original substrates by means of sonication. To that end, the substrates were fully immersed in isopropanol and then submitted to
an ultrasonic bath for a few minutes. Power and duration of the bath were adjusted to obtain dispersions with suitable nanowire concentrations in all cases.

For the nanowire integration in the μHPs and subsequent alignment between the IDEs, dielectrophoretic forces were used [5] applying an AC square signal (15 V peak-to-peak) to the electrodes. One or more drops of the nanowire’s dispersion were deposited on top of the IDE using a microsyringe. The frequency of the signal was then adjusted for each material to achieve an optimum coverage and alignment of nanowires.

After the deposition and induced alignment of the nanowires across the IDE, the resulting devices were kept at 100°C for 2 hours to facilitate the full evaporation of the solvent residues.

2.3. Device test and characterization methods

The resulting devices were first electrically tested; Current-Voltage (I-V) curves were acquired with a dual-channel Keithley SourceMeter Unit (SMU) model 2600 and custom-made LabView software. Shielded coaxial wires, fixings and test chambers were used to minimize noise in the electrical measurements due to the high resistance of some devices. In temperature controlled experiments, the microheater of the μHPs was also powered by the second SMU channel of the same instrument. The calibration curves provided by the manufacturer and in-house validated were used to estimate the temperature reached by the μHP. The direct comparison of the device resistance values at different microheater operating conditions and those obtained as a function of increasing current level without the heater was used to estimate the equivalent temperature reached due to the self-heating effect [23,35].

In gas sensing experiments, accurate gaseous environments were maintained inside the test chamber with mass flow controllers mixing dry synthetic air (SA, 21% O₂ and 79% N₂), and CO (100 ppm ± 1% in SA). These lab-class gases contained less than 5 ppm/vol of CₙHₘ and H₂O.
For experiments under illumination, a Hamamatsu LC8 light source with a type [01] Hg-Xe lamp enhanced for the line at $\lambda = 365$ nm was used. UV light intensity impinging on the devices was determined with the help of a thermopile detector (FieldMax-TOP).

Ten devices of each type were fabricated and tested showing the typical responses presented in the following sections, in a reproducible manner for more than 12 weeks.

3. RESULTS AND DISCUSSION

3.1. Device fabrication

The fabrication process consisted of three steps (Figure 1.a): (1) transfer of nanowires from the growth substrate to a liquid suspension, (2) drop casting on top of the Inter Digital Electrodes (IDE) and, simultaneously, (3) nanowire positioning and alignment using dielectrophoretic forces. All these three steps can be controlled macroscopically and are scalable to the necessary production level in industry in a cost effective manner.

Going into details, nanowires (NW) were first removed from the substrate by direct sonication in isopropanol. The materials properties (length, stiffness, density, etc.) determined the optimum sonication time and necessary power to achieve a suitable concentration of dispersed nanowires. As a rule of thumb, concentrations in the order of 100 NW/μl were appropriate in our experiments. Care was taken to prevent excessive nanowire fracture during the sonication step, as the final nanowires length had to be comparable to the IDE spacing.

Figures 1.b, 1.c and 1.d show the devices after the alignment step of SnO$_2$, ZnO and TiO$_2$ nanowires respectively. Frequencies of 10 kHz, 4 MHz and 5 MHz were applied in these three cases. Remarkably, the process was successful, independently on the materials composition, dimensions and polar nature. It is noteworthy that the reported conditions depend on the materials, solvent and electrode design used. Therefore, the optimization of the process in a
different set up will certainly require different parameters that could be optimized according to the extensive literature [3–5].

In all cases, nanowires concentrated in the inter-electrode region aligned parallel to each other, and perpendicular to the electrode edges. Finite elements simulations with Accelrys COMSOL Multiphysics 4.3 of the electric field distribution across the two electrodes (Figure 1.e) showed that the nanowires mainly aligned parallel to the direction of the local electric field and concentrated in the regions with highest field strengths, which was fully determined by the layout of the commercial electrodes used.

This validates (1) that dielectrophoresis is a suitable macroscopic technique to manipulate and align nanowires, and (2) that the fabrication methodology is flexible enough to be applied to different kinds of metal oxides (3) without the need for a special electrode design.

Further experiments showed that fine tuning of the number of nanowires positioned across the IDEs could be achieved by adjusting the concentration of nanowires in the dispersion, the number of drops deposited and the applied AC frequencies used, as function of the material and geometry.

### 3.2. Electrical properties

According to SEM micrographs (Figure 1.b to 1.e), the nanowires bridged the insulating gap across the IDE after the positioning step. To assess the electrical quality of the contacts, current-voltage (I-V) curves were acquired. Figures 2.a, 2.b and 2.c show that current flowed through the nanowires in all cases. The average DC resistance was $R_{\text{SnO}_2} = 10.5 \pm 0.1 \ \text{M}\Omega$, $R_{\text{ZnO}} = 42 \pm 1 \ \text{M}\Omega$ and $R_{\text{TiO}_2} = 0.72 \pm 0.05 \ \text{M}\Omega$, at room temperature (25°C). Resistance values up to 10 $\Omega$ were measured between electrodes after depositing and drying several drops of pure isopropanol, confirming that the observed conductance can only be assigned to the nanowires.
For SnO$_2$, an entirely Ohmic behavior was observed, whilst in the case of ZnO and TiO$_2$ the I-V curves were nonlinear in the range of tested temperatures. This effect is explained by the nature of the metal/semiconductor contacts that develops between the Au, and the metal oxides, which is reported to be nearly Ohmic for as-grown SnO$_2$ [36], and rectifying for ZnO [37] and TiO$_2$ [38] due to the formation of Schottky barriers. In fact, similarly high resistance contact values are found in single wire devices, fabricated with certain nanolithography methods [39].

To further verify the characteristics of the conduction path built by the nanowires, the dependence of the device resistance as function of the temperature was measured, observing a clear drop in all cases as temperature increased (Figure 2.a to 2.c). Interestingly, after this heating process, no change in the device resistance at room temperature was observed, indicating that the electrical contact was already stable after solvent evaporation.

It is clear, however, that these resistance values were high, considering the typical resistance of a single nanowire [25,39,40] and taking into account the high number of nanowires connected in parallel. This fact may indicate (1) that not all the nanowires were effectively contacted and/or (2) the nanowire/metal contacts quality was very poor (which is plausible in case of different materials in soft contact [41]).

Concerning contact stability, specific experiments showed that the resistance baseline of the devices displayed less than 2% drift after 2 weeks of continuous operation at 200ºC. Additionally, current-voltage curves acquired repeatedly on the same device for 15 days, showed differences of less than 0.1% in average. Both facts are evidences that the contacts are stable and solid. In fact, similar contacts are present in commercial metal oxide sensors based fabricated by direct screen printing of nanoparticles slurries. In such commercial devices no further metallization is used.
Nevertheless, our results show that this integration methodology is suitable to effectively connect nanowires with metal electrodes, without the need of any subsequent metallization steps. As shown in the following sections, the electrical continuity achieved, despite clearly improvable, is sufficient to take advantage of the favorable properties of single-wire devices.

3.3. Application to gas sensing

In self-heating operation mode, the current applied to probe the resistance of a nanowire dissipates enough power (in the \( \mu \)W range) to heat up the nanostructure to temperatures sufficiently high (hundreds of \(^\circ\)C) to thus activate the thermal response to gases [23].

Figure 3.a shows that this phenomenon is clearly noticeable in SnO\(_2\)-based devices, which is the most attractive material for gas sensing applications. At very low probing currents (0.1 nA), no gas response was observed to different concentrations of CO diluted in dry SA. As the probing current increased, the modulation of the resistance appeared in presence of the target gas (CO); e.g. a factor 6 at \([\text{CO}] = 100\) ppm. Using the resistance dependence of the nanowire material with temperature, equivalent operating temperatures up to 200\(^\circ\)C could be estimated. At this temperature, the devices detected CO concentrations much lower than the ones shown here (down to 5 ppm). In all cases (Figure 3.b), the resistance modulation followed the expected power law \( \frac{R_{SA}}{R_{CO}} \propto [\text{CO}]^n \) typical for MOX sensors [41]. At the optimum temperatures for sensing, the exponent was estimated to be \( n = 0.5 \pm 0.1 \) in agreement with the values predicted by theoretical models for the interaction between SnO\(_2\) and CO predict (\( n_{\text{theory}} = \frac{1}{2} \) [41]), suggesting that the here reported devices operate following the conventional sensing mechanisms in MOX sensors.

The responses obtained at equivalent temperatures were compared; fixed either with self-heating or using the calibrated microheater (Figure 3.c). In both experiments, equivalent
responses were obtained but their dynamics were clearly different. This fact may originate from differences in the local temperature achieved by each nanowire in self-heating mode, which leads to an overall response signal that averages the dynamics of nanowires operating at different temperatures [42].

Concerning power consumption, our devices exhibited figures in the order of 200 μW to reach temperatures of 200°C, which is remarkably low and comparable to those obtained with complex devices based on single nanowires [23]. It goes without saying that this feature is an additional step forward towards heater-free solid-state sensor technology such as the one proposed by Monereo et al. [42].

Besides, reproducing pulsed operation mode was also feasible as shown in Figure 3.d. The response time\(^1\) of the resistance modulation to probing current changes (i.e. temperature) was in the order of tens of ms, both in the heating and cooling transients. These values are again comparable to the figures obtained with individual nanowires [43], sufficiently fast to study sudden surface-gas interactions [24], and clearly much faster than values reported for gas sensor based on thin films [44].

All these results demonstrate that our devices possess all the advantages commonly attributed to gas sensors based on individual nanowires; namely: (1) large responses, (2) good signal stability, (3) fast response dynamics, and (4) ultra-low power consumption in fast self-heating operation mode.

### 3.4. Application to photodetectors

\(^1\) Resistance stabilization to thermal changes was fitted to an exponential law for the heating and cooling semi periods. Response times were defined as the exponential time constant of the transient.
ZnO is one of the most promising materials for optoelectronic applications in the ultraviolet range [12], with remarkably high sensitivity when shaped in the form of nanowires [25–27]. According to the literature, an ordered arrangement of a few nanowires is necessary to reach such high values [45].

Figure 4.a shows the typical photocurrent generated in one of our ZnO-based devices upon exposure to UV light pulses, at two different bias conditions. Clearly (Figure 4.b), the photocurrent ($I_{ph}$) scales proportionally to the flux of photons ($\Phi_{ph}$) and as function of the bias voltage ($V_{bias}$), as expected for a photoconductor device [45]. This behavior leads to normalized photoconductive gains\(^2\) ($g_{ph}$) [45] in the order of $g = 10^{-7}$ m\(^2\)/V, to be compared with the best values in the literature $g_{Lit}^{NW} = 10^{-5}$ to $10^{-6}$ m\(^2\)/V reported for single-wire devices [27,45], and $g_{Lit}^{TF} = 10^{-8}$ m\(^2\)/V reported for thin film devices [46].

From a dynamic perspective, our devices ($\tau \sim 10$ s) were slightly faster than conventional single-wire devices ($\tau_{Lit}^{NW} \sim 30$ s [45]), but still much slower than thin film ones ($\tau_{Lit}^{TF} \sim 1.5$ µs [46]). These differences can be fully explained by taking into account the strong influence of surface-mediated electron-hole separation effects in nano-size materials [26]: charge separation slows down the electron-hole recombination times (and thus the response times), leading to larger photocurrent values.

Again, the optoelectronic performance of the devices herein implemented is (1) sufficient for UV photodetection applications, (2) fully comparable to that of devices made with much more

\(^2\) For the calculations of $g_{ph}$, according to the definitions in Ref. [45], an average density of 0.4 nanowire/µm along the electrode edges and nanowire diameters of 150 nm were assumed to estimate the width of the light collection area ($W$). As for the inter electrode distance ($L$) manufacturer specifications (10 µm) were used. This way, after geometry ($W,L$) and bias voltage ($V_{bias}$) correction, $g_{ph}$ estimations at different $V_{bias}$ were fully consistent.
complex fabrication methods (e.g. single-wire devices), and (3) unexpectedly good, taking into account the moderate quality of the wire-to-metal and wire-to-wire contacts.

3.5. Application to Field Effect Transistors

Our results indicate that the fabrication method is even suitable to build up field-effect devices as well. To that end, the pair of IDE electrodes were used as source (label S) and drain (label D), to define a conduction channel along all the parallel aligned nanowires. The tungsten microheater, which was embedded in the substrate under the nanowires in a dielectric SiO$_2$ layer, was used as gate (label G) terminal. The current-voltage characteristics of these FET devices made of ZnO nanowires show (Figure 5.a) that the conduction along nanowires can be effectively modulated by a gate voltage $V_G$. To determine the efficiency of the gating behavior, transconductance measurements ($I_{SD}$ vs $V_G$) were obtained at a variety of $V_{SD}$ values (Figure 5.b), observing a typical n-type behaviour. The threshold voltages were around -4 V for all $V_{SD}$ values. The on-off current ratio ($I_{ON}/I_{OFF}$) was $\sim$ 30 at $V_{SD} = 5$ V, which is comparable to other results reported in the literature with more complex fabrication approaches [18,47].

From the transconductance plots, the mobility ($\mu$) and carrier concentration ($n_e$) can be estimated by using the expressions for a conduction channel built in one single nanowire [14],

\[
\frac{dI_{sd}}{dV_G} = \frac{\mu C}{L^2} \tag{1}
\]

\[
C = \frac{2\pi\varepsilon_0\varepsilon_r L}{\ln\left(\frac{2h}{d}\right)} \tag{2}
\]

\[
n_e = \frac{V_{th} C}{q\pi\left(\frac{d}{2}\right)^2 L} \tag{3}
\]

where $C$ is the surface capacitance of a nanowire, $\varepsilon_r$ is the dielectric constant ($\varepsilon_r = 4$) and $h$ the thickness (3 $\mu$m) of the SiO$_2$ gate dielectric, $V_{th}$ is the threshold voltage, $d$ is the nanowire diameter (150 nm), $q$ is the electron charge, and $L$ is the length of the nanowire channel. The
IDE spacing (10 μm) has been taken as L, since several nanowires (two or three, typically) are needed to bridge across both IDEs. Our system is composed of several (N) nanowires connected in parallel. Thus, assuming that the total current (I_{SD \text{ Total}}) flows evenly through them, one can rewrite eq.(1), (2), and (3) as,

\[ I_{SD \text{ Total}} = \sum_{i=0}^{N} I_i = N \cdot I_i \quad \text{eq.(1)} \]
\[ \frac{1}{N} \frac{dI_i}{dV_G} = \frac{\mu C_{\text{Total}}}{L^2} \]  

\[ C_{\text{Total}} = \sum_{i=0}^{N} C_i = N \cdot C_i \]  

\[ n_e = \frac{V_{th} C_i}{q \pi \left( \frac{d}{2} \right)^2 L} \]  

where I_i and C_i are the current and the surface capacitance of each single nanowire, which are assumed to be identical.

Figure 5.c shows the carrier mobility (μ) as a function of the number of nanowires (N) effectively connected between the IDE, calculated with eq.(4), (5) and (6) and the slope of the I_{SD} vs V_G plot at V_{SD} = 4 V (Figure 5.b). Carrier mobilities ranging from 3000 to 0.3 cm² V⁻¹ s⁻¹ have been estimated, assuming that 1 to 100 nanowires were connected. Considering the typical mobility values for ZnO nanowires reported in the literature (from 2 to 30 cm² V⁻¹ s⁻¹ [48]), one can estimate that 10 to 40 nanowires were effectively connected. This is plausible taking into account SEM images that show that not all the nanowires paths completely connect both sides of the IDE. Moreover, the previous calculations led to carrier concentration values of \( n_e = (1.3 \pm 0.7) \cdot 10^{17} \text{ cm}^{-3} \), in agreement with previously reported values [14].

These final results open the door to develop in future works field-effect devices based on this simple assembly technique.

4. CONCLUSIONS
In summary, a simple approach to integrate metal oxide nanowires in electronic devices based on dielectrophoretic alignment has been presented. The method is flexible enough to manipulate different materials and nanowire dimensions with conventional electrode designs using exclusively macroscopic solution-based techniques.

In fact, our results demonstrate that fully functional devices, which display all the advantages of single-nanowire-based gas sensors, photodetectors, and field-effect transistors, are obtained right after the assembly step, and no additional metallization is required. This means that most of the design constraints typically imposed and attributed to dielectrophoretic methods (e.g. special needle-like electrode designs, post-metallization steps, etc.) [3–5] can be relaxed for many applications. Additionally, the method displays potential to address other applications in which multi-nanowire configurations are much sought after, such as electrocatalysis or photoelectrocatalysis.

This represents an important improvement in the race for solving the challenge of integrating nanomaterials into microdevices, and opens up new possibilities for low cost manufacturing of general-purpose electronic and transducer devices based on high quality 1D nanostructures, ranging from simple metal oxide nanowires to more complex (core shell, decorated, etc.) structures.
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Figure 1. (a) Fabrication process steps, including: nanowire suspension preparation, drop transfer to the final substrate, and nanowire alignment with dielectrophoretic forces. This facile methodology was successfully applied to multiple metal oxide nanowires, such as (b) SnO₂, (c) ZnO, (d) TiO₂, etc. (e) According to Finite Elements simulations, the nanowire arrangement (in concentration and direction) follows the electric field distribution imposed by the electrode (IDE) geometry.
Figure 2. Typical Current-Voltage characteristics of the three kinds of devices produced: (a) SnO$_2$, (b) ZnO, and (c) TiO$_2$. Resistance dependence with temperatures is consistent with the semiconductor nature of the nanowires.
Figure 3. (a) Resistance evolution in presence of several CO concentrations, recorded at different probing current levels. (b) Summary of the device response (defined as $R_{SA}/R_{CO}$) as a function of the carbon monoxide concentration [CO] at different probing currents in self-heating operation. The corresponding power dissipation and equivalent temperature are indicated. (c) Comparison of the responses to 100 ppm of CO diluted in dry SA obtained in equivalent conditions with self-heating and with an external heater. (d) Resistance changes in response to variations of the probing current (pulsed self-heating). Exponential fittings and time constants are shown.
Figure 4. (a) Photocurrent generated at different light intensities ($\Phi_{\text{ph}}$) and bias voltages ($V_{\text{bias}}$).
(b) Summary of the photocurrent response as a function of photon flux ($\Phi_{\text{ph}}$), where the slope is a direct measurement of $g_{\text{ph}}$, after geometry (W,L) and bias voltage ($V_{\text{bias}}$) correction [45].
Figure 5. (a) Current $I_{SD}$ vs voltage $V_{SD}$ curves recorded at different gate voltages from 0 to 4 V. (b) Current $I_{SD}$ vs gate voltage $V_G$ of the same device measured at bias voltage from 0 to 4 V. (c) Estimated carrier mobility $\mu$ as a function of number N of nanowires effectively connected across the IDE. Typical ZnO mobility values for bulk and nanowires are marked as hashed regions [48].
REFERENCES


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